

Form PTO 1449
(Modified)U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY DOCKET NO.
244085US2SERIAL NO.
NEW APPLICATION

LIST OF REFERENCES CITED BY APPLICANT

APPLICANT
Yukinori HIROSEFILING DATE
HEREWITH

GROUP

U.S. PATENT DOCUMENTS

| EXAMINER INITIAL | | DOCUMENT NUMBER | DATE | NAME | CLASS | SUB CLASS | FILING DATE IF APPROPRIATE |
|---------------------|----|--------------------|------|------|-------|--------------|-------------------------------|
| | AA | | | | | | |
| | AB | | | | | | |
| | AC | | | | | | |
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| | AK | | | | | | |
| | AL | | | | | | |
| | AM | | | | | | |
| | AN | | | | | | |

FOREIGN PATENT DOCUMENTS

| | | DOCUMENT NUMBER | DATE | COUNTRY | TRANSLATION | |
|----------|----|--------------------|----------|--|-------------|----|
| | | | | | YES | NO |
| <i>W</i> | AO | 2000-321224 | 11/24/00 | Japan (with English Abstract) | | X |
| | AP | 2810370 | 07/31/98 | Japan (with English Translation of Claim 1 and Advantageous Effect of the Invention) | | X |
| | AQ | 2002-5857 | 01/09/02 | Japan (with English Abstract) | | X |
| | AR | 9-274883 | 10/21/97 | Japan (with English Abstract) | | X |
| <i>W</i> | AS | 8-115699 | 05/07/96 | Japan (with English Translation of Claim 1 and Advantageous Effect of the Invention) | | X |
| | AT | | | | | |
| | AU | | | | | |
| | AV | | | | | |

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

| | | |
|----------|----|---|
| <i>W</i> | AW | Seiichi SUZUKI, "Introduction to EBSP Method and its Advantages with Nano Probe Schottky FE-SEM", Materia Japan, Vol. 40, No. 7, March 22, 2001, pp. 612-616 (With English Extract) |
| <i>W</i> | AX | Seiichi SUZUKI, "Crystal Structure Microanalysis of Metal Surface Using EBSP Method", IDEMA Japan News, No. 38, pp. 8-14 (with English Extract) |
| | AY | |
| | AZ | |

☐ Additional References sheet(s) attachedExaminer *[Signature]*Date Considered *7/16/01*

*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.